

implanted ions in step (1) with silicon in the substrate, and a top silicon layer including the said major surface isolated by the buried layer.

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2. (Amended) The method of claim 1 wherein the said first kind of ions is oxygen ions, so as to form the buried layer as a buried oxide layer.

sub B6
3. (Amended) The method of claim 1 wherein the said first kind of ions is nitrogen ions, so as to form the buried layer as a buried nitride layer.

4. (Amended) The method of claim 1 wherein the said first dose is determined by the desired thickness of said buried layer, which will be formed after said annealing process in the step (3).

A2
6. (Amended) The method of claim 1 wherein the said first energy is chosen to form enough depth of said buried layer after said annealing process in step (3), so as to form a desired thickness of the top silicon layer.

A3
11. (Amended) The method of claim 1 wherein the said second dose is chosen in the range from $1 \times 10^{13} \text{ cm}^{-2}$ to $5 \times 10^{16} \text{ cm}^{-2}$ to form an amorphous region beneath the major surface containing both a majority of top silicon layer and all the buried layer, which is formed in step (3).

A4
16. (Amended) The method of claim 2 further comprising the following steps for eliminating silicon islands and pinholes in the buried oxide layer of SOI material:

(1) implanting silicon ion, germanium ion, inert gas ion or oxygen ion at a dose and an energy into SOI material containing top silicon layer and buried oxide layer at a temperature below 100°C , to form an amorphous region including said buried oxide layer and to keep the original structure in vicinity of said major surface; and

(2) annealing aforesaid SOI material at a temperature in the range from 900°C to 1250°C to restore structure of every layer and to eliminate silicon islands and pinholes in said buried oxide layer.

85 ✓ 19. (Amended) The method of claim 2 wherein the third temperature is chosen to be in the region from 1250° to below silicon melting point, for elimination threading dislocations in the top silicon layer and reducing surface dislocations to the lowest density to form SOI material.

20. (Amended) The method of claim 2 wherein the third temperature is selected in the range from 900° to 1250°C, for eliminating threading dislocations in the top silicon layer, and silicon islands and pinholes in buried oxide layer to form SOI material.

sub 27 ✓ 21. (Amended) The method of claim 3 wherein the said first dose is in the range from $1 \times 10^{16} \text{ cm}^{-2}$ to $5 \times 10^{18} \text{ cm}^{-2}$.

22. (Amended) The method of claim 3 wherein the said first energy is chosen to form enough depth of said buried nitride layer after said annealing process in step (3), so as to form a desired thickness of the top silicon layer.

23 ✓ sub 27 ✓ 24. (Amended) The method of claim 3 wherein the said first temperature is chosen to keep the original structure in vicinity of said major surface on silicon containing substrate in said first implantation process of step (1).

25 ✓ sub 27 ✓ 26. (Amended) The method of claim 3 wherein the said second energy is chosen in the range from 30keV to 5MeV to form an amorphous region beneath the said major surface and to keep the original structure in the major surface of said silicon containing substrate during the implantation in step(2).

27. (Amended) The method of claim 3 wherein the said second dose is chosen in the range from $1 \times 10^{13} \text{ cm}^{-2}$ to $5 \times 10^{16} \text{ cm}^{-2}$ to form an amorphous region beneath the major surface containing both a majority of top silicon layer and all the buried oxide layer, which is formed in step(3).
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mlb7 28. (Amended) The ~~method~~ of claim 3 wherein the said second kind of ion is silicon ion.

At cut 29. (Amended) The method of claim 3 wherein the said second kind of ion is germanium ion.

30. (Amended) The method of claim 3 wherein the said second kind of ion is inert gases ion.

31. (Amended) The method of claim 3 wherein the said second kind of ion is oxygen ion.

32. (Amended) The method of claim 3 wherein further comprising an oxygen ion implantation process before said step (2) at the same energy as the first one, at a dose for easily forming amorphous structure from buried oxynitride layer, which will be formed in the annealing process of step (3).

EXPLANATION OF AMENDMENT:

The claims have been amended as shown by [deletions] and insertions.

1. (Amended) A method for fabricating a silicon-on-insulator (SOI) material [by using an implanting oxygen ions into] on a silicon containing substrate having a major surface, comprising the steps of:

(1) implanting [oxygen] first kind of ions at a first dose and a first energy through said major surface into said silicon containing substrate controlled at a first temperature;

(2) implanting second kind of ions at a second dose and a second energy through said major surface into said silicon containing substrate at a second temperature below 100°C, to form an amorphous region beneath the major surface and to keep the original structure in the major surface of said silicon containing substrate; and

(3) annealing aforesaid silicon containing substrate at a third temperature in the range from 900° to below the melting point of silicon, to form a buried [oxide] layer by combining

[oxygen] the first implanted ions in step (1) with silicon in the substrate, and a top silicon layer including the said major surface isolated by the buried [oxide] layer.

2. (Amended) The method of claim 1 wherein the said [third temperature is chosen to be in the region from 1250°C to below silicon melting point, eliminating the threading dislocations in the top silicon layer and reducing the surface dislocations to the lowest density to form SOI material] first kind of ions is oxygen ions, so as to form the buried layer as a buried oxide layer.

3. (Amended) The method of claim 1 wherein the said [third temperature is selected in the range from 900°C to 1250°C, eliminating the threading dislocations in the top silicon layer, and silicon islands and pinholes in buried oxide layer to form SOI material] first kind of ions is nitrogen ions, so as to form the buried layer as a buried nitride layer.

4. (Amended) The method of claim 1 wherein the said first dose is determined by the desired thickness of said buried [oxide] layer, which will be formed after said annealing process in the step (3).

6. (Amended) The method of claim 1 wherein the said first energy is chosen to form enough depth of said buried [oxide] layer after said annealing process in step (3), so as to form a desired thickness of the top silicon layer.

11. (Amended) The method of claim 1 wherein the said second dose is chosen in the range from $1 \times 10^{13} \text{ cm}^{-2}$ to $5 \times 10^{16} \text{ cm}^{-2}$ to form an amorphous region beneath the major surface containing both a majority of top silicon layer and all the buried [oxide] layer, which is formed in step (3).

16. (Amended) [A] The method of claim 2 further comprising the following steps for eliminating silicon islands and pinholes in the buried oxide layer of SOI material [formed by using SIMOX method, comprising the steps of]:

(1) implanting silicon ion, germanium ion, inert gas ion or oxygen ion at a dose and an

energy into SOI material containing top silicon layer and buried oxide layer at a temperature below 100°C, to form an amorphous region including said buried oxide layer and to keep the original structure in vicinity of said major surface; and

(2) annealing aforesaid SOI material at a temperature in the range from 900°C to 1250°C to restore structure of every layer and to eliminate silicon islands and pinholes in said buried oxide layer.

19. (Amended) [A] The method of claim 2 wherein the third temperature is chosen to be in the region from 1250° to below silicon melting point, for elimination threading dislocations in the top silicon layer and reducing surface dislocations to the lowest density to form SOI material [for forming high quality of SOI material on a silicon containing substrate having a major surface by using SIMNI method, comprising the steps of:

(1) implanting nitrogen at a first dose and a first energy through said major surface into said silicon containing substrate controlled at a first temperature;

(2) implanting second kind of ion at a second dose and a second energy through said major surface into said silicon containing substrate at a second temperature below 100°C, to form an amorphous region beneath said major surface and to keep the original structure in said major surface of the silicon containing substrate; and

(3) annealing aforesaid silicon containing substrate at a third temperature in the range from 900°C to below the melting point of silicon, to combine the first implanted nitrogen and silicon and to form a buried nitride layer and a top silicon layer, which includes said major surface, isolated by the buried nitride layer].

20. (Amended) The method of claim [9] 2 wherein the third temperature is selected in the range from 900° to 1250°C, for eliminating threading dislocations in the top silicon layer, and silicon islands and pinholes in buried oxide layer to form SOI material [said first dose is chosen to form a desired thickness of said buried nitride layer after said annealing process in step (3)].

21. (Amended) The method of claim [20] 3 wherein the said first dose is in the range from $1 \times 10^{16} \text{ cm}^{-2}$ to $5 \times 10^{18} \text{ cm}^{-2}$.

22. (Amended) The method of claim [19] 3 wherein the said first energy is chosen to form enough depth of said buried nitride layer after said annealing process in step (3), so as to form a desired thickness of the top silicon layer.

24. (Amended) The method of claim [19] 3 wherein the said first temperature is chosen to keep the original structure in vicinity of said major surface on silicon containing substrate in said first implantation process of step (1).

26. (Amended) The method of claim [19] 3 wherein the said second energy is chosen in the range from 30keV to 5MeV to form an amorphous region beneath the said major surface and to keep the original structure in the major surface of said silicon containing substrate during the implantation in step(2).

27. (Amended) The method of claim [19] 3 wherein the said second dose is chosen in the range from $1 \times 10^{13} \text{ cm}^{-2}$ to $5 \times 10^{16} \text{ cm}^{-2}$ to form an amorphous region beneath the major surface containing both a majority of top silicon layer and all the buried oxide layer, which is formed in step(3).

28. (Amended) The method of claim [19] 3 wherein the said second kind of ion is silicon ion.

29. (Amended) The method of claim [19] 3 wherein the said second kind of ion is germanium ion.

30. (Amended) The method of claim [19] 3 wherein the said second kind of ion is inert gases ion.

31. (Amended) The method of claim [19] 3 wherein the said second kind of ion is oxygen ion.

32. (Amended) The method of claim [19] 3 wherein further comprising an oxygen ion implantation process before said step (2) at the same energy as the first one, at a dose for easily forming amorphous structure from buried oxynitride layer, which will be formed in the annealing process of step (3).